

FDS #0104

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## INFORMATION DISCLOSURE CITATION

## U.S. PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Name	Class	Sub-Class	Filing Date
EP	US 6,587,581 B1	07/01/03	Matsuyama et al.	382	149	
EP	US 6,521,890 B2	02/18/03	Ishitani et al.	250	309	
EP	US 2002/0185597 A1	12/12/02	Ikku et al.	250	309	
EP	US 6,476,398 B1	11/05/02	Xu et al.	250	396	
EP	US 2002/0158199 A1	10/31/02	Takane et al.	250	310	
EP	US 6,332,962 B1	12/25/01	Athas et al.	204	192.34	
EP	US 5,916,424	06/29/99	Libby et al.	204	298.36	
EP	US 5,302,828	04/12/94	Monaham	250	307	

## FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB-CLASS	TRANSLATION YES OR NO
EP	JP7312195	11/28/95	JAPAN	H01J37	22	ABSTRACT
EP	JP7254387	10/03/95	JAPAN	H01J37	22	YES
EP	JP2226001	09/07/90	JAPAN	G01B11	00	ABSTRACT

## OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

	Saitoh, K.; Takeuchi, S.; Moriizumi, K.; Watakabe, Y.; Kato, T.; "Electron beam pattern inspection system using digital image processing". J. Vac. Sci. Technol. B; 4(3), pp. 686-691 (May 1986)		
	Osamu Nasu; Katsuhiro Sasada; Mitsuji Ikeda; Makoto Ezumi; "New CD-SEM System for 100-nm Node Process". Hitachi Rev. 51(4) pp.125-129 (2002).		
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EP	Kurt Laken; "Advanced Pole Analysis: A New Tool for Measuring Pole Tip Recession". VEECO Brochure (2002)		
Examiner:	Svan Pert	Date Considered:	6/26/06

Examiner: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.